

## **Dainippon Screen Secures Top Share in Worldwide Market for Semiconductor Cleaning Equipment in Three Key Fields**

Kyoto, Japan -- May 19, 2010 -- Dainippon Screen Mfg. Co., Ltd. secured the top share in the worldwide market for its semiconductor cleaning equipment in three key fields in 2009, holding fast to its position as an industry leader for three consecutive years starting in 2007. With a 69.7% share in single wafer spray processors\*, an 81.3% share in auto wet stations\*\*, and an 85.2% share in scrubbers\*\*\*, the company expanded its share in all equipment fields compared to the previous year.

Even amid the global recession that began in the fall of 2008, Dainippon Screen enjoyed a steady increase in shipments to Taiwan in 2009, as the semiconductor industry showed some signs of recovery during the second half of the year. The company secured a 69.7% share in single wafer spray processors, which represents a 9.4% increase year-on-year (60.3% in 2008). It also secured an overwhelming market share in both auto wet stations (81.3%; up from 57.4% in 2008) and scrubbers (85.2%; up from 80.1% in 2008). In this way, Dainippon Screen continues to maintain a commanding position in the worldwide market for semiconductor cleaning equipment.

Dainippon Screen remains committed to providing a varied line of cleaning equipment that meets customer needs and to further strengthening its product competitiveness and service systems, whose excellence is proven by its market share. Moreover, Dainippon Screen intends to further enhance customer satisfaction as it contributes to technical innovation in the semiconductor industry.

**\* Single wafer spray processors**

Equipment that cleans individual wafers with a chemical spray. Single wafer spray processors process smaller volumes of wafers than batch cleaning equipment (300 wafers per hour using Dainippon Screen equipment), but provides excellent cleaning performance.

**\*\* Auto wet stations**

Equipment that cleans multiple wafers simultaneously in a chemical bath. Auto wet stations are capable of processing large volumes of wafers (650 wafers per hour using Dainippon Screen equipment) and is suited to high volume production.

**\*\*\* Scrubbers**

Equipment that is used in processes where wafers can be cleaned using only deionized water. Scrubbers clean wafers physically with a soft brush and deionized water.

Source: "Market Share: Semiconductor Etch and Clean Process Equipment, Worldwide, 2009"; Authors: Dean Freeman, Takashi Ogawa, Mark Stromberg, Klaus Rinnen, and Barbara Van, (Gartner Research; Published on April 19, 2010) (Revenue from Shipments of Single Wafer Processors, Auto Wet Stations and Scrubbers, Worldwide)